



- L2: (5) test and deep adj ▲
- L3: (105) deep adj trench ▲
- L4: (1) S and substrate a
- L5: (0) S and substrate a
- L6: (55) S and substrate
- L8: (0) S and substrate a
- L9: (46) S and substrate
- L10: (43) S and substrate ▼

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DBs USPAT EPO JPO

Default operator OR Exact Highlight all non-referential only

deep adj trench adj capacitor and word adj lineS1

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|----|-------------------------------------|--------------|------------|-------|---|---------------------------|---------------------------|
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| 39 | <input checked="" type="checkbox"/> | US 6037194 A | 20000314 | 37 | Method for making a DRAM cell with grooved transistor | 438/147 | 438/147; |
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| 41 | <input checked="" type="checkbox"/> | US 6033967 A | 20000307 | 8 | Method for increasing capacitance in DRAM | 438/398 | 438/395; |
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| 43 | <input checked="" type="checkbox"/> | US 6025245 A | 20000215 | 7 | Method of forming a trench capacitor with a sacrificial | 438/243; | |
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| 45 | <input checked="" type="checkbox"/> | US 6013548 A | 20000111 | 70 | Self-aligned diffused source vertical transistors with | 438/242 | 257/E27.101; 438/143; |
| 46 | <input type="checkbox"/> | US 5998821 A | 19991207 | 19 | Dynamic ram structure having a trench capacitor | 257/301 | 257/296; 217/311; |
| 47 | <input checked="" type="checkbox"/> | US 5998820 A | 19991207 | 16 | Fabrication method and structure for a DRAM cell | 257/296 | 257/296; 257/301; |
| 48 | <input checked="" type="checkbox"/> | US 5995410 A | 19991130 | 7 | Multiplication of storage capacitance in memory cells | 365/149 | 365/149; |